



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Applicant: Steven R. Walther  
Serial No: 09/586,492  
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For: Method and Apparatus for Controlling Ion Implantation During Vacuum Fluctuation  
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CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, Washington, D.C. 20231 on September 27, 2001.

*[Signature]*  
Lisa A. Fletcher

Attn: Official Draftsperson  
Commissioner for Patents  
Washington, DC 20231

LETTER TO OFFICIAL DRAFTSPERSON

Sir:

In response to the Notice of Allowability dated July 2, 2001, enclosed are four (4) sheets of FORMAL DRAWINGS for Figures 1-4 for the above-referenced patent application.

Respectfully Submitted,

*[Signature]*  
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